

SUBSTRATE PROCESSING DEVICE, METHOD FOR CONTROLLING SUBSTRATE
PROCESSING DEVICE, AND STORAGE MEDIUM STORING A PROGRAM

ABSTRACT

A substrate processing device for processing a substrate, comprising an image sensor configured to detect positions of two corners on at least one diagonal of a substrate when the substrate is transferred to a predetermined position; an illuminating device that can be disposed so as to illuminate the two corners of the substrate on an opposite side of the substrate at the predetermined position relative to the image sensor; and a control device configured to determine the position of the substrate on the basis of the positions of the two corners, which are detected by the image sensor, the control device being configured to be capable of changing at least either light quantity or wavelength of output light of the illuminating device.

Representative drawing: Fig. 15A